

Notice of Allowability	Application No.	Applicant(s)
	10/814,627	YASUI ET AL.
	Examiner	Art Unit
	Toniae M. Thomas	2822
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to the amendment filed on 23 October 2006.		
2. The allowed claim(s) is/are <u>2-9</u> .		
 3. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some* c) None of the: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 		
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application. THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		
4. A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.		
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached		
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date		
(b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date		
Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).		
 DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL. 		
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. ☐ Notice of Informal Pa	atent Application
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary Paper No./Mail Date	(PTO-413), e
3. Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date	7. 🗌 Examiner's Amendr	
 Examiner's Comment Regarding Requirement for Deposit of Biological Material 		nt of Reasons for Allowance
•	9. Other	
	M - W	ilczewski ary Examiner
	Prim	ary txaminer.
U.S. Patent and Trademark Office		X/DC

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Drawings

1. The replacement-drawing sheets received on 23 October 2006 are acceptable.

Reasons for Allowance

2. The following is an examiner's statement of reasons for allowance: the prior art of record does not anticipate, teach or suggest a semiconductor manufacturing method substantially as claimed. Specifically, it is known in the art to: form a silicon nitride film along an inner wall of a trench in a semiconductor substrate, form an embedded insulator film inside the trench, and convert a portion of the silicon nitride film into a non silicon nitride type insulator film, as evidenced by the prior art reference to Ahn et al. (US 2002/0168873). However, the prior art of record fails to anticipate, teach or suggest - either separately or combined, a semiconductor device manufacturing method substantially as claimed, wherein the method comprises: forming a first embedded insulator film inside the trench, such that the trench is not completely filled; and converting a portion of the silicon nitride film exposed from the embedded insulator into a non silicon nitride type insulator, whereby a portion of the silicon nitride film remains between the embedded insulator and the inner wall of the trench.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should

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preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Toniae M. Thomas whose telephone number is (571) 272-1846. The examiner can normally be reached on Monday through Friday from 8:30 a.m. to 5:30 p.m.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

TMT 12 November 2006

> M. Wilczewski Primary Examiner TC 2800